

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	5935	29/602.1,605,606.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:44
S2	6718	336/65,83,200,206-208,220-223, 232.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:40
S3	708	257/531.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:40
S4	6239	438/238,381,106,107.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:41
S5	7	LIANG-MORRIS-p-f.in. or CHUANG-SWAY.in. or FAN-FRANK-k-c.in. or KAO-CHEN-chung.in.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:43
S6	3	S5 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:00
S7	8308	29/602.1,605,606,846.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:44
S8	6	("5448822" "5576680" "5852866" "5877924" "6015742" "6441715").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2006/07/18 09:45
S9	10	S1 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:01
S11	36	S2 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:01
S12	7	S9 and S11	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:04
S13	1307	inject\$3 with (conduct\$3 or metal\$3) with (coil or (coil near winding))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S14	1733	216/39;41.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S15	164	photolithography with photoresist with coil	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07

EAST Search History

S16	4	S13 and S15	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S17	1	(US-6600404-\$).did.	USPAT	OR	ON	2006/07/18 10:14
S18	3	S17 and "fig." S6	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S19	0	S17 and FIG	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S20	0	S17 and fig	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S21	1	S17 and photoresist	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15


[Home](#) | [Login](#) | [Logout](#) | [Access Information](#) | [Alerts](#) |

Welcome United States Patent and Trademark Office

Search Results

[BROWSE](#)[SEARCH](#)[IEEE XPLORE GUIDE](#)

Results for "(((coil) <and> photoresist)<in>metadata)) <and> (pyr >= 1950 <and> pyr <= 2002)"

e-mail

Your search matched 11 of 1373978 documents.

A maximum of 100 results are displayed, 25 to a page, sorted by Relevance in Descending order.

» Search Options

[View Session History](#)[New Search](#)

Modify Search

(((coil) <and> photoresist)<in>metadata)) <and> (pyr >= 1950 <and> pyr <= 2002)

Search

☐ Check to search only within this results setDisplay Format: ☒ Citation ☐ Citation & Abstract

» Key

IEEE JNL IEEE Journal or Magazine

IEE JNL IEE Journal or Magazine

IEEE CNF IEEE Conference Proceeding

IEE CNF IEE Conference Proceeding

IEEE STD IEEE Standard

[view selected items](#)[Select All](#) [Deselect All](#)

- ☐ 1. **Thermomechanical head performance**
Pust, L.; Rea, C.J.T.; Gangopadhyay, S.;
[Magnetics, IEEE Transactions on](#)
Volume 38, Issue 1, Part 1, Jan. 2002 Page(s):101 - 106
Digital Object Identifier 10.1109/TMAG.2002.988919
[AbstractPlus](#) | [References](#) | Full Text: [PDF\(282 KB\)](#) IEEE JNL
[Rights and Permissions](#)
- ☐ 2. **Design and performance of a recessed thin film inductive transducer**
Zak, B.S.; Curland, N.; Giusti, J.H.; Ash, K.P.; Cameron, G.P.;
[Magnetics, IEEE Transactions on](#)
Volume 32, Issue 1, Jan. 1996 Page(s):74 - 79
Digital Object Identifier 10.1109/20.477553
[AbstractPlus](#) | Full Text: [PDF\(656 KB\)](#) IEEE JNL
[Rights and Permissions](#)
- ☐ 3. **Design study and fabrication techniques for high power density microtra**
Brunet, M.; O'Donnell, T.; O'Brien, J.; McCloskey, P.; O'Mathuna, C.;
[Applied Power Electronics Conference and Exposition, 2001. APEC 2001. Sixt](#)
[IEEE](#)
Volume 2, 4-8 March 2001 Page(s):1189 - 1195 vol.2
Digital Object Identifier 10.1109/APEC.2001.912516
[AbstractPlus](#) | Full Text: [PDF\(652 KB\)](#) IEEE CNF
[Rights and Permissions](#)
- ☐ 4. **Dry-etching of barium-strontium-titanate thin films**
Schneider, S.; Mono, T.; Albrethsen-Keck, B.; Melaku, Y.; Waser, R.;
[Applications of Ferroelectrics, 1998. ISAF 98. Proceedings of the Eleventh IEE](#)
[Symposium on](#)
24-27 Aug. 1998 Page(s):51 - 54
Digital Object Identifier 10.1109/ISAF.1998.786634
[AbstractPlus](#) | Full Text: [PDF\(612 KB\)](#) IEEE CNF
[Rights and Permissions](#)
- ☐ 5. **High density plasma etching of aluminum alloys**
Bradley, S.; Ching-Hwa Chen; Kovall, G.;
[VLSI Multilevel Interconnection Conference, 1991. Proceedings., Eighth Intern:](#)
11-12 June 1991 Page(s):298 - 300

Digital Object Identifier 10.1109/VMIC.1991.153005

[AbstractPlus](#) | Full Text: [PDF\(320 KB\)](#) IEEE CNF
[Rights and Permissions](#)

- ☐ 6. **A universal electromagnetic microactuator using magnetic interconnecti**
Sadler, D.J.; Liakopoulos, T.M.; Ahn, C.H.;
[Microelectromechanical Systems, Journal of](#)
Volume 9, Issue 4, Dec. 2000 Page(s):460 - 468
Digital Object Identifier 10.1109/84.896766
[AbstractPlus](#) | [References](#) | Full Text: [PDF\(188 KB\)](#) IEEE JNL
[Rights and Permissions](#)
- ☐ 7. **Fabrication of submicron trackwidth thin film head and its inductance-sa**
characteristics
Du, H.; Pan, G.;
[Magnetics Conference, 2002. INTERMAG Europe 2002. Digest of Technical P](#)
[International](#)
28 April-2 May 2002 Page(s):AQ6
Digital Object Identifier 10.1109/INTMAG.2002.1000666
[AbstractPlus](#) | Full Text: [PDF\(228 KB\)](#) IEEE CNF
[Rights and Permissions](#)
- ☐ 8. **Micromachined spiral inductors using UV-LIGA techniques**
Sadler, D.J.; Gupta, S.; Ahn, C.H.;
[Magnetics, IEEE Transactions on](#)
Volume 37, Issue 4, Part 1, July 2001 Page(s):2897 - 2899
Digital Object Identifier 10.1109/20.951340
[AbstractPlus](#) | [References](#) | Full Text: [PDF\(152 KB\)](#) IEEE JNL
[Rights and Permissions](#)
- ☐ 9. **Comparison of $\kappa < 3$ silicon oxide-based dielectric pre-copper metallization**
processes using black diamond
Mandal, R.P.; Cheung, D.; Wai-Fan Yau; Cohen, B.; Rengarajan, S.; Chou, E.;
[Advanced Semiconductor Manufacturing Conference and Workshop, 1999 IEE](#)
8-10 Sept. 1999 Page(s):299 - 303
Digital Object Identifier 10.1109/ASMC.1999.798250
[AbstractPlus](#) | Full Text: [PDF\(464 KB\)](#) IEEE CNF
[Rights and Permissions](#)
- ☒ 10. **Novel Fabrication Of Electroplated 3D Micro-Coils Using 3D Photolithogr**
Photoresist
Yoon, J.-B.; Han, C.-H.; Yoon, E.-S.; Kim, C.-K.;
[Microprocesses and Nanotechnology Conference, 1998 International](#)
13-16 July 1998 Page(s):85 - 86
[AbstractPlus](#) | Full Text: [PDF\(264 KB\)](#) IEEE CNF
[Rights and Permissions](#)
- ☐ 11. **Low Temperature Processing Of Coil Insulating Photoresist By Electron I**
Jennison, M.J.; Young K. Kim;
[MMM-Intermag Conference, 1998. Abstracts., The 7th Joint](#)
6-9 Jan. 1998 Page(s):64 - 64
[AbstractPlus](#) | Full Text: [PDF\(92 KB\)](#) IEEE CNF
[Rights and Permissions](#)